

FORM PTO-1449 (Modified) INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)		Docket No. 01SC062US2	Application Number
		Applicants: James Chingwei Li, et al	
		Filing Date	Group Art Unit

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

V9	E. G. Colgan, R.J. Polastre, M. Takeichi and R.L. Wisniewi, <u>Thin-Film-Transistor Process-Characterization Test Structures</u> , February 12, 1998, http://www.research.ibm.com/journal/rd/423/polastre.txt

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
(2-92) Patent and Trademark Office